A Nano Coordinate Machine for Optical Dimensional Metrology

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Project Objectives

Develop a non-contact, high precision sensor based upon a DVD auto-focusing probe.

Integrate said probe with high precision stage with software interfact to create a functional nano-cmm system.

Validate both the probe and the system through testing.



Auto-Focusing Probe Theory

- Laser is directed towards surface through objective lens
- Reflected signal passes through beam splitter and on to Photodiode Array
- Object surface must be near perpendicular to beam



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Auto-Focusing Probe Theory

- Reflected spot shape is detected by photodiode array and error signal is generated
- Error signal is used to reposition objective lens to maintain focus



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Nano-CMM System

- Fibermax 6-axis stage with 10 nanometer resolution in x-y directions, 2 nm in z direction
- Invar frame for minimum flex and expansion
- Sony KHS-220 optical pickup
- NI 12-bit analog DAQ card
- VB User Interface





Gear Cross Section



Gear Cross Section Profile Measurement



Edge Detection

Cross-section
of 1.22 mm
diameter
microball

Circle fit to acquired data



Dimensions in mm



Repeatability



•50 Data points at one location

All points within 200 nm range



CD Surface Measurement

CD tracks can
be seen as
raised red lines

Nominal trackpitch is 1.6 um

Nominal track width is 0.6 um





Three Hole Gear Surface



Photograph, Raw Data, and Processed Data from Three Hole Gear

